

AMENDMENTS TO THE CLAIMS:

Kindly amend claims 1-4, and add claim 5, as shown below.

This listing of claims will replace all prior versions and listings of claims in the
Application:

Claim 1 (currently amended). A ~~noncontact conductivity~~ measuring instrument for
noncontact measurement of conductivity of a silicon wafer using a microwave, the ~~noncontact~~
~~conductivity~~ measuring instrument ~~characterized by including~~comprising:

an oscillator ~~which performs oscillation of~~ for oscillating the microwave;

a circulator ~~which is~~ connected to the oscillator;

a horn antenna ~~which is~~ connected to the circulator, the horn antenna transmitting the
microwave to ~~a sample~~ the silicon wafer and receiving a reflected wave from a surface of the
silicon wafer;

a detector ~~which is~~ connected to said circulator, the detector outputting a voltage
proportional to a square of magnitude of the ~~received microwave~~ reflected wave; and

a computer for ~~computing means for inputting said voltage to compute~~ computing
conductivity of said silicon wafer from said voltage.

Claim 2 (currently amended). A ~~noncontact conductivity~~ measuring instrument according to
claim 1, ~~characterized in that~~ wherein said circulator is ~~in contact with~~ connected to the
oscillator through an isolator.

Claim 3 (currently amended). A ~~noncontact conductivity~~ measuring instrument according to
claim 1, ~~characterized in that~~ wherein a frequency of the microwave oscillating in said
oscillator is 94 GHz ~~when a silicon wafer is measured~~.

Claim 4 (currently amended). A ~~noncontact conductivity~~ measuring instrument according to claim 2, ~~characterized in that~~ wherein a frequency of the microwave oscillating in said oscillator is 94 GHz ~~when a silicon wafer is measured~~.

Claim 5 (new). A conductivity measuring instrument for noncontact measuring of conductivity of a silicon wafer using a microwave, the measuring instrument comprising, in combination:

an oscillator for oscillating of the microwave;

a circulator connected to the oscillator;

a horn antenna connected to the circulator, the horn antenna transmitting the microwave to the silicon wafer and receiving a reflected wave from a surface of the silicon wafer;

a detector connected to said circulator, the detector outputting a voltage proportional to a square of magnitude of the reflected wave; and

a computer for computing conductivity of said silicon wafer from said voltage.

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